

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re application of

: **ATTN: BOX RCE**

Yoshio YANASE et al.

: **Confirmation No. 6344**

Serial No. 09/856,982

: Docket No. 2001\_0615A

Filed May 30, 2001

: Group Art Unit 2877

METHOD FOR INSPECTING  
SEMICONDUCTOR WAFER SURFACE

: Examiner Sang H. Nguyen

**PETITION FOR EXTENSION OF TIME**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEES FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

Sir:

Petition hereby is made for a two month extension of time to respond to the communication of June 3, 2003.

The fee of \$420.00 is

(X) submitted herewith.  
( ) to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.

( ) Small entity status of this application is established by a Small Entity Status Assertion which  
( ) is enclosed.  
( ) has been previously submitted.

Respectfully submitted,

Yoshio YANASE et al.

11/31/2003 EFLORES 00000048 09050562

FC:1252

470.00 US

By

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October 30, 2003